

AMENDMENTS TO THE CLAIMS

1. **(Currently Amended)** A support assembly for supporting a substrate holder during substrate processing, comprising:

a substrate holder support configured to support a substrate holder and to be supported by ~~prevent rotational slippage of the substrate holder support relative to a~~ rotational drive for rotating the substrate holder support; and

a retaining member configured to couple the substrate holder support to the rotational drive to thereby prevent rotational slippage of the substrate holder support relative to the rotational drive, the retaining member being selectively removable from the substrate holder support and the rotational drive.

2-9. **(Canceled)**

10. **(Currently Amended)** The support assembly of Claim [[4]] 1, ~~wherein further comprising the rotational drive, the rotational drive comprising~~ is an elongated shaft having a longitudinal axis and an outer surface, the shaft having at least one indentation in the outer surface, the indentation being configured to be engaged by the retaining member.

11. **(Original)** The support assembly of Claim 10, wherein the at least one indentation comprises three indentations, the retaining member being configured to engage with any one of the indentations.

12. **(Original)** The support assembly of Claim 11, wherein the three indentations are spaced apart equally about a perimeter of the shaft.

13. **(Original)** The support assembly of Claim 10, wherein one end of the shaft includes a tapered surface and the at least one indentation is located on the tapered surface.

14. **(Original)** The support assembly of Claim 10, wherein the at least one indentation consists of only one indentation.

15. **(Currently Amended)** The support assembly of Claim 10, wherein the retaining member[[,]] and the at least one indentation of the shaft are configured so that the retaining member does not prevent the substrate holder support from being lifted vertically with respect to the shaft when the retaining member is inserted into both the opening and the at least one indentation.

16. **(Currently Amended)** The support assembly of Claim [[4]] 1, wherein the retaining member comprises a ceramic material.

17. **(Original)** The support assembly of Claim 16, wherein the retaining member comprises quartz.

18. **(Currently Amended)** The support assembly of Claim [[4]] 1, ~~wherein~~ further comprising the rotational drive, the rotational drive comprising ~~comprises~~ a shaft having at least one indentation, ~~and the substrate holder support comprising~~ comprising ~~comprises~~ a socket configured to receive a portion of the shaft, the support having an opening located in a sidewall of the socket, the support being configured so that insertion of the retaining member into the opening engages the retaining member with the at least one indentation in the shaft to prevent rotation of the substrate holder support with respect to the shaft.

19. **(Original)** The support assembly of Claim 18, wherein the opening and the at least one indentation, when aligned, together form a passage configured to receive the retaining member.

20. **(Original)** The support assembly of Claim 18, wherein the opening comprises an elongated slot, the retaining member being sized and configured to be received within and occlude substantially the entire length of the slot.

21. **(Original)** The support assembly of Claim 20, further comprising a lock for selectively securing the retaining member in the slot.

22-23. **(Canceled)**

24. **(Currently amended)** The support assembly of Claim 18, wherein the retaining member has a first end and a second end oriented generally transverse to the first end, the first end configured to be inserted into the opening in engagement with the shaft indentation, the first end being rotatable within the opening such that the second end is movable between a first position and a second position, wherein when the second end is in the second position the first end is prevented from being pulled out of the opening and the indentation by a securing element of the substrate holder support bearing against the second end, and wherein when the second end is in the first position the first end can be freely pulled out of the opening and the indentation.

25. **(Original)** The support assembly of Claim 18, wherein the opening is substantially cylindrical and the retaining member includes a substantially cylindrical end portion configured to be removably and slidably inserted into the opening.

26. **(Original)** The support assembly of Claim 25, wherein the end portion of the retaining member is configured to substantially fill the opening.

27. **(Canceled)**

28. **(Original)** The support assembly of Claim 18, wherein the substrate holder support is configured to support a substrate holder for holding a semiconductor wafer.

29. **(Currently Amended)** The support assembly of Claim 28, further comprising the substrate holder, wherein the substrate holder is configured to support a 300 mm wafer.

30. **(Currently Amended)** The support assembly of Claim 18, further comprising the substrate holder, wherein the substrate holder comprises a susceptor.

31. **(Original)** The support assembly of Claim 18, wherein the substrate holder support includes a plurality of arms extending generally radially outward and upward from the socket, the arms configured to support a substrate holder.

32-37. **(Canceled)**

38. **(Currently Amended)** The support assembly of Claim [[4]] 1, wherein the retaining member secures the substrate holder support to the rotational drive to prevent rotational slippage while allowing the substrate holder support to be lifted free of the rotational drive.

39. **(Currently Amended)** A substrate processing system, comprising:

a support member having a receptor and a plurality of arms extending generally radially outward from the receptor, the arms being configured to support an underside of a substrate holder, the receptor having a ~~an~~ hole in a sidewall of the receptor;

a locking key; and

an elongated [[a]] rotational linkage having an end portion configured to be received within the receptor such that the rotational linkage is at least partially rotatable with respect to the receptor about a longitudinal axis of the rotational linkage, the end portion having at least one retaining surface, the at least one retaining surface and the hole configured so that when the rotational linkage is rotated to a locking position, the at least

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one retaining surface and the hole together form a passage sized and configured to receive the locking key in a manner such that the locking key prevents the support member from rotating independently of the rotational linkage.

40. **(Original)** The system of Claim 39, wherein the locking key locks the support member to the rotational drive with respect to rotationally and horizontally applied forces without locking the support member to the rotational drive with respect to vertically applied forces.

41-65. **(Canceled)**